



## Radiation hard fast electronics for LHC experiments

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- Some brief historical remarks
- Requirements for LHC
- Choice of technology
- Radiation effects on electronics
- Examples try to relate effects to CMS implementations
- Final comments
- Assumptions
  - This talk deals only with on-detector electronics
  - Audience is not circuit designers or electronics professionals





- Expected radiation levels were unprecedented
  - ~10Mrad in tracking regions
  - experience of failures at below krad levels
- Customised electronics was essential
- Several space-qualified processes, mostly of military origin
  - SoS, SoI, bipolar, GaAs, hardened CMOS,...
  - at least as many companies...
- Space system methodology not applicable
  - shielding plus qualification of commercial components
- As well as technology, there were several important other issues, primarily...
  - government regulation
  - cost





## **Requirements for LHC experiments**





- Major factors which influence electronics design and implementation
  *directly*
  - Clock speed
  - Storage time
  - Readout rate
  - Granularity
  - Data volume

#### indirectly

- Integrated L (radiation)
- Operating temperature
- T stability

#### implied

- Operating voltages
- Power
- Performance

	р-р	Pb-Pb
Luminosity	10 <sup>34</sup> cm <sup>-2</sup> s <sup>-2</sup>	10 <sup>27</sup> cm <sup>-2</sup> s <sup>-2</sup>
Annual integrated L	5x10 <sup>40</sup> cm <sup>-2</sup>	
CM Energy	14 TeV	5.5 TeV/N
$\sigma_{inelastic}$	~70mb	~6.5b
Interactions/bunch	~20	0.001
Tracks/unit rapidity	~140	3000-8000
Beam diameter	20µm	20µm
Bunch length	75mm	75mm
Beam crossing rate	40MHz	8MHz
Level 1 trigger delay	≈3.2µs	≈3.2µs
Mean L1 trigger rate	<100kHz	<8kHz





#### • <u>All</u> electronics are in a radiation environment at LHC

	physics	technical	
Tracking	high spatial precision large channel count limited energy precision limited dynamic range	low power ~ mW/channel high radiation levels ~10Mrad	
Calorimetry	high energy resolution large energy range excellent linearity very stable over time	intermediate radiation levels ~0.5Mrad power constraints	
Muons	very large area moderate spatial resolution accurate alignment & stability	low radiation levels       1 Gray = 100 rads	





- functions required by all systems
  - amplification and filtering
  - analogue to digital conversion
  - association to beam crossing
  - storage prior to trigger
  - deadtime free readout @ ~100kHz
  - storage pre-DAQ
  - calibration
  - control
  - monitoring

- Special functions for Calorimeters and Muon systems
  - first level trigger primitive generation
  - (so far not feasible for tracking)
- example







- As usual, there are several ways of doing the same thing
  - Ideally, take a system view from early design stage
- May be hard to say in advance which is best but decisions have consequences, eg:
- A-D conversion
  - On-detector = power, custom components,...
  - Off-detector = no of links, cost,..
- Link technology
  - Electrical: power, speed, noise issues,..
  - Optical: cost, technical challenges,...







- Performance
- Power consumption
- Circuit size
- Programmability
- Uniformity
- Quality (Yield = fraction of working circuits)
- Testability
- Translate into choice of technology, cost, impact on detector, flexibility and ease of use,...
  - example: power

Power dissipated in circuits is only part of the problem

Impact on detector design

- Long resistive cables typically consume more power than active electronics
  - weight, cooling,...
- Consequent impact on material budget, especially for interior regions of experiment









- Data stored in pipeline memory with "ring" topology
- Pointers record current (write) location and location of data being read
- Addresses of used locations stored in FIFO to be skipped during writing
  - pipeline length is dynamic
- Pipeline length, buffer depth, storage time chosen to ensure that rate of data lost is sufficiently small
  - queuing problem







## Choice of technology





- CMOS has become the preferred technology
- Modern CMOS meets LHC speed and power constraints
- It has been shown to be very radiation hard
- Quality and uniformity has been demonstrated to be high
- Commercial electronics is dominated by CMOS
  - It is very costly to swim against the stream
- HEP is a very small community compared to industry
  - Largest LHC orders <1000 wafers</p>
  - Commercial foundry production >40,000 wafers per month
- There are benefits from adopting a few common technologies and standards





- All considered, and some are used..
- GaAs intrinsically hard to high level
  - few processes, not analogue
- Sol/SOS CMOS (Silicon on Insulator, Silicon on Sapphire)
  - investigated but excessive noise
- Hardened CMOS
  - few specialised processes, even fewer foundry services
  - most to ~1Mrad
  - expensive
- bipolar neutron sensitive, especially power devices
  - ICs tolerant to high level but observed dose & rate effects





## **Radiation effects**

# Basic bipolar radiation effects

- Transistor operation
  - Carriers flow from emitter to collector, via base
  - Recombination in base controls transistor action (gain)
- Effects of radiation
  - Hadrons cause atomic displacement
    - Traps (band gap energy levels)
    - Increased carrier recombination in base
- Consequences
  - gain degradation, transistor (mis-)matching, dose rate dependence
- NB bipolar processes can also be sensitive to surface effects
  - like CMOS





## CMOS transistor operation

- Reminder of basic FET physics
  - bias "metal" gate to deplete substrate
  - beyond a certain threshold voltage, substrate does not deplete deeper
  - instead "inversion layer" created
- Inversion layer
  - <u>extremely</u> shallow, at oxidesilicon interface
  - carriers mobile in applied field
- Transistor operation
  - Modulation of source-drain current via V<sub>gate</sub>

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- Inversion layer is so shallow that bulk damage has no effect
  - so CMOS is hard against neutrons
- Real oxide contains trapped (positive) charge at interface
  - Compensated for during manufacturing process
- Charged particle and gamma irradiation generates carriers in oxide
  - become trapped at Si-SiO<sub>2</sub> interface
  - interface traps influence short-term behaviour
    - details depend on bias
- Consequences
  - threshold (gate) voltage shift,
  - leakage current through or around transistor (especially NMOS)







- Latch-up can affect all technologies
  - charging of surface layers influences charge in substrate
  - parasitic bipolar devices draw current, and can be destructive
  - generally avoided by technology design
- Single event effects **non-permanent** 
  - Iarge ionisation charge deposited within device, usually from recoiling ion
  - Some of the charge collected on sensitive circuit node
  - Influences voltage and can change state of node
  - Important for digital logic
  - Essentially undetectable at the time
  - But can be mitigated by design, including majority logic circuits





- Thermal noise
  - Quantum-statistical phenomenon; carriers in constant thermal motion
    - macroscopic fluctuations in electrical state of system
  - Typically associated with input transistor or resistive components
- Shot noise
  - Random fluctuations in DC current flow
  - Typically associated with sensor
- 1/f noise
  - commonly associated with interface states in MOS electronics
  - Luckily, less important for high speed electronics
- In a properly designed amplifier system, the dominant noise sources should be at the input
  - Generally can ignore noise sources after front-end





- Gate shot noise is negligible insulating gate and no curre
- Thermal noise voltage from channel

$$e_n^2 = 4kT\gamma(\frac{2}{3g_m})\Delta f$$

Transconductance

• 
$$C_{ox} = \varepsilon_{ox} / t_{ox}$$

- W/L = transistor width/length
- 1/f noise usually unimportant (for LHC)
- Implications
  - To achieve low noise, aim for large W/L and large (tolerable)  ${\rm I}_{\rm DS}$
  - but  $C_{amp} = C_{ox}WL$  and require capacitance matching:  $C_{amp} \approx C_{det}/3$
  - Mobility is also T dependent  $\mu(T) \sim T^{-3/2}$

$$g_m = \sqrt{2\mu C_{ox} I_{DS} \left(\frac{W}{L}\right)}$$



C = capacitance T = temperature  $\Delta f$  = bandwidth  $\mu$  = mobility (v/E)





Once noise sources are known, their impact can be calculated







#### pMOS preferred for lower 1/f noise







#### Threshold voltage



## Why so radiation tolerant?



#### Gate oxide scaling



After N.S. Sacks, M.G. Ancona, and J.A. Modolo, IEEE Trans.Nucl.Sci., Vol.NS-31 (1984) 1249

- Electron tunneling neutralizes trapped holes in thin oxides.
- Total dose effects, such as V<sub>t</sub> shift, are naturally reduced in deep submicron processes.

M. Letheren CERN

## Radiation tolerant design



### Thin gate-oxides + Gate all-around layout

#### Min-size NMOS layout

- Edge-less structure eliminates leakage via parasitic edge transistor.
- Guard ring eliminates leakage between devices and provides latch-up protection.
- Higher capacitance of gate all-around structure improves SEU tolerance.
   Further SEU tolerance by circuit design (SEU-tolerant flip-flops) or system design (triple-redundant logic, error detection and correction coding etc.)







- Small dimensions and multi-levels of metal allow room for many useful programmable features...
  - internal control of bias currents, voltages (shaping time, etc)
  - capacitor values (by summing/switches)
  - adjustable thresholds (via DAC)
  - switchable gains, signal polarity, signal processing
  - standard interfaces (I<sup>2</sup>C, LVDS,...)
  - redundant logic, for SEU effects
  - internal self-calibrate
- Many of these are vital for evaluation and large scale test
  - or tuning during operation





## **Examples from CMS**

## CMS Tracker Electronic System





- Main features
  - Analogue readout
  - No on-detector zero suppression
  - Optical analogue data transfer
  - Control signals sent optically
  - Local electrical transfer
- Only 0.25µm ASICs
  - APV25
    - ~100,000 die, inc spares
  - Complete control system
    - 5000 20000 die of:
    - DCU, PLL, CCU, LD...
    - LVDSbuf/mux

ACT: 3 March 2005



- Main features
  - 128 readout channels
  - 50 ns CR-RC amplifier
  - 192 cell pipeline memory
  - alternate operating modes
    - peak, deconvolution, multi-mode
    - on-chip analogue signal processing
  - on-chip ancillary functions
    - eg calibration, I<sup>2</sup>C, programmable latency...







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7.1mm

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V <sub>supply</sub>	0 - 2.5V
Power/channel	1.9mW analogue + 0.4mW digital
Input transistor	pMOS W/L= 2000/0.36 I <sub>DS</sub> = 400µA
Filtering	50ns CR-RC or 3 weight analogue sum (deconvolution)
Pipeline length	192 cells, including 32 [max] cells readout buffer



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- Some process <sup>100</sup> optimisation was necessary in early production runs due to heavy <sup>(S)</sup> <sup>100</sup> 60 use of one metal layer
- Common to many other HEP designs







- One of many complex images and details provided of foundry process and monitoring...
- Illustrates the importance of good cooperative relationship with vendor







- Only minor effects after irradiation
  - Compensated for by minor tuning of parameters at long intervals during operation





- True for noise and other parameters
  - plots now "uninteresting"





- High resolution crystal calorimeter
  - requires  $\sigma/E = 0.5\%$ , with 16 bit dynamic range



- MGPA: multi-gain amplifier
- 12-bit ADC: CMS collaboration with specialist design house
- FENIX: multi-function digital chip VHDL translation to ASIC
- 0.25µm control ASICs developed for tracker
- high speed 0.25µm GOL optical link driver

Now all based on 0.25µm CMOS





- High gain channel is most crucial
  - should hold most interesting physics
- Higher noise tolerable on lowest gain range
  - because electronics not dominant







#### Specifications

Parameter	Barrel	End-Cap	calibrate - for functionality
Full-scale signal	60pC	16pC	verification
Rms noise	10,000 e (1.6fC)	3,500 e (0.56fC)	120 setting channel onset
Input capacitance	~200pF (APD)	~50pF (VPT)	
Gain ranges	1, 6, 12		
Gain tolerance	±10%		
Linearity	0.1% full scale (each range)		1 - PSMF = Vpk-25
Pulse shape (impulse)	40ns CR-RC		
Channel to channel pulse shape matching	<1%		
Supply voltage	0 - 2.5V (0.25µm CMOS)		- Урк-25
Output signals to ADC	Differential 1.8V, ±0.45V around ≈1.25V		0

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•Additional requirements:





- Gain switching allows to achieve dynamic range and resolution
  - Custom ADC required to match amplifier at acceptable cost
  - ASIC approach allows 3 identical ADCs in single chip
  - and ensure radiation hardness
- Single MGPA design with external components satisfies both barrel and endcap  $C_{f}$  $R_{f}$ 0.2
- Large PMOS input
  - 30,000/0.36,  $I_{DS} = 20mA \rightarrow C_{GS} \sim 60pF$ ,  $g_m \sim 0.3S$

Barrel

- needed for short rise-time, C<sub>det</sub> ~ 200pF (barrel)
- MGPA power = 600mW
- In this case, significant noise sources apart from input transistor
- Noise dominated by R<sub>f</sub> (little C<sub>f</sub> influence)
  - happily noise scales for endcap in right ratio

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## The future

# Relevant technology trends



- 0.25µm CMOS probably available until ~2009
  - 0.18µm and 0.13µm already available
    - radiation hardness looks good
    - 300mm wafers next standard, already in use
  - Supply voltage reduction (0.13µm 1.2V/1.5V)
    - challenge for designers
  - Power consumption remains a major issue
    - trend to higher speed and lower power applications
      - but reduced voltages may not imply reduced currents
    - more digital logic possible in smaller area
      - programmable functions to tune, correct, test, debug,...?





F.Faccio et al CERN

Not much difference between edgeless and normal transistors







- ASICs are now <u>vital</u> for HEP experiments
  - but...
- Electronics technology is still advancing rapidly
  - and we are forced to follow technology trends
- There are huge potential benefits from doing so
- Final thought
  - ASIC technology is undoubtedly expensive
    - foundry cost in Y2000 ~\$2B
    - manufacturing increasingly targets major consumers
  - Yet (round figure!) production costs (2005) of
    - CMS Silicon sensor ~10CHF/cm<sup>2</sup>
    - CMS 0.25µm ASIC wafer ~10CHF/cm<sup>2</sup>
- Thanks to many CMS colleagues for data and information